

Department of Electrical & Computer Engineering  
Dalhousie University

ECED 4260  
IC Design and Fabrication  
Final Examination

Instructor: Y. Ma  
Exam date: Dec. 6, 2006  
Exam duration: 180 minutes  
Aids permitted: This is a closed book exam. No books or notes are to be consulted.  
Three double-sided 8.5"x11" formula sheets are allowed.

- Instructions:
1. Provide your name printed, signature and I.D. number on this page.
  2. Verify that this booklet contains 9 pages (including the cover page).
  3. Neatly enter your answers in the spaces provided.
  4. Use the reverse sides of the pages for rough work.

Student name: Reference Solution

Signature: \_\_\_\_\_

Student ID: \_\_\_\_\_

Question	Time (min)	Worth	Mark	Subject
1	40	25		VDHL, Combinational logic
2	30	10		Design of Fast Adder
3	15	8		Booth Multiplication
4	25	12		Floating Point Numbers
5	40	30		Digital System Testing
6	30	15		IC Fabrication
Total	180 min	100		

Question 1. (20 marks)

1.1 (6 marks) By writing directly in the code, correct 6 errors which would be detected by a VHDL compiler. Label the corrections.

-- some kind of finite state machines --  
entity ever is

```
port (clock, clear, enable: in bit;
      y1, y0, done: out bit); -- ①
end ever; -- ② inout
```

architecture what of ever is  
signal next\_y1, next\_y0: bit;

```
begin
next_y1 <= ((y1 and not y0 and not enable) or
            (y1 and y0) or (not y1 and y0 and enable)) and not clear;
next_y0 <= (not y1 and enable) or (not y1 and y0) or (y0 and not enable) or clear;
done <= y1 and not y0;
```

$$y_1 \cdot \bar{y}_0 \cdot \bar{e}n + y_1 \cdot y_0 + \bar{y}_1 \cdot y_0 \cdot e n + \bar{y}_1 \cdot e n + \bar{y}_1 \cdot y_0 + y_0 \cdot \bar{e}n + c\bar{a}$$

```
state: process (clock)
begin
```

```
if clock'event and clock='1' then
y1 <- next_y1; -- ③ ←
y0 <- next_y0; -- ④ ←
endif; -- ⑤ end if;
end process ever;
end what; -- ⑥ state
```

1.2 (9 marks) Create minimal sum-of-product expressions for next\_y1, next\_y0 and done.

Next_y1		y1,y0 =			
		00	01	11	10
clear,enable=	00			1	1
	01		1	1	
	11				
	10				

Next\_y1 =  $y_1 \bar{e}n \cdot \bar{c}\bar{a} + y_0 \cdot e n \cdot \bar{c}\bar{a}$

Next_y0		y1,y0 =			
		00	01	11	10
clear,enable=	00				
	01				
	11				
	10				

Next\_y0 =  $clear + y_0 \cdot \bar{e}n + \bar{y}_1 \cdot e n$

if clear=1 next\_y0=1  
next\_y1=0

01

$y_1 + y_0 + c \cdot e n$

$y_1 y_0$	00	01
00	00	01
01	01	11
11	11	10
10	10	00

2/5

2/5

done		y1,y0 =			
		00	01	11	10
clear,enable=	00				1
	01				1
	11				1
	10				1

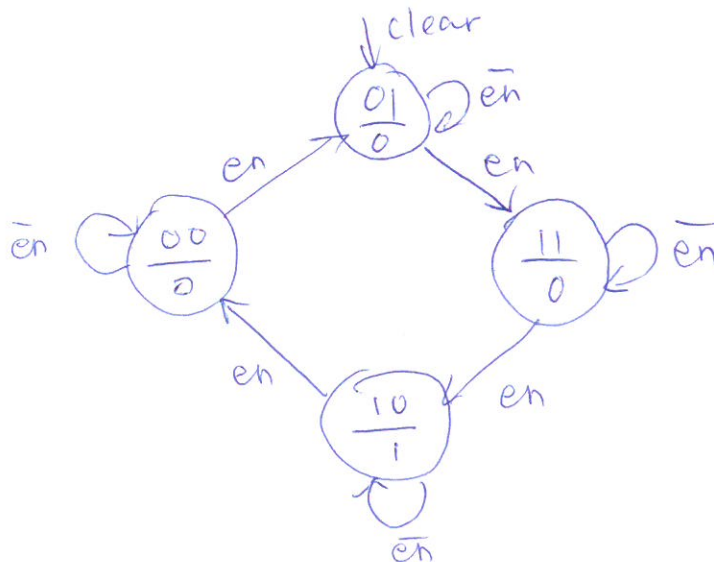
1/5

done =  $\bar{y}_0 y_1$

1.3 (6 marks) Trace the execution of the VHDL code (with the reasonable corrections made). Assume that enable and clear have settled before any clock edge. Fill in the values that the signals would take on after they become stable following any clock edge.

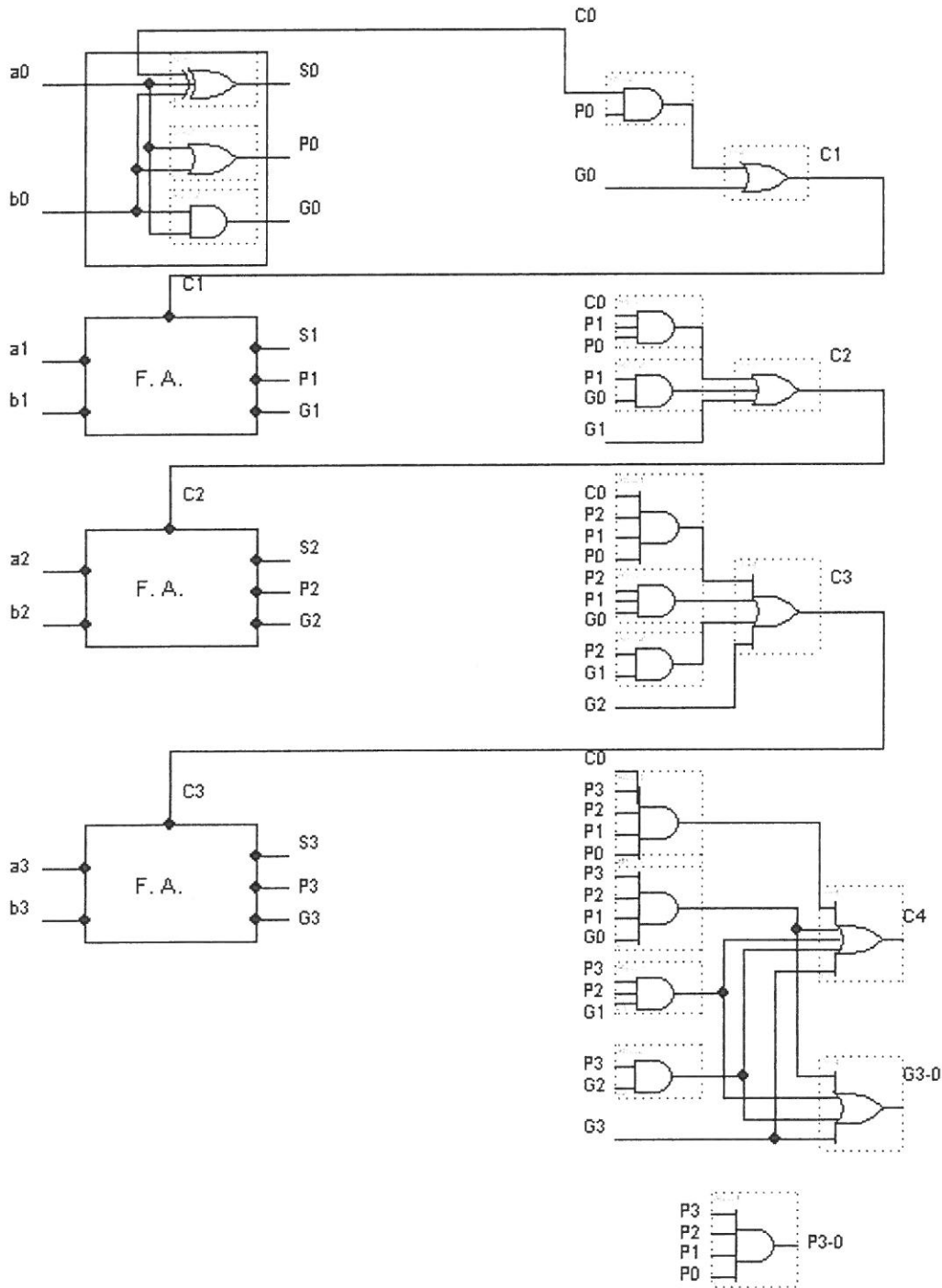
enable	clear	clock	next_y1	next_y0	y1	y0	done
0	0	1	0	0	0	0	0
0	1	↓	0	1	0	0	0
1	1	0	0	1	0	0	0
1	0	↑	1	1	0	1	0
1	0	1	1	1	0	1	0
1	1	↓	0	1	0	1	0
1	0	↑	1	0	1	1	0
0	0	↑	1	1	1	1	0
1	1	↑	0	1	0	1	0
1	0	↑	1	0	1	1	0
1	0	↑	0	0	1	0	1
1	0	↑	0	1	0	0	0
1	0	↑	1	1	0	1	0

1.4 (4 marks) Draw a state transition graph for the finite state machine.



Question 2. (10 marks)

2.1. (5 marks) Observe the structural regularity of the 4-bit carry look-ahead (CLA) adder circuit given and derive the sum-of-product expressions of a 6-bit CLA adder for  $C_4$ ,  $C_5$ ,  $C_6$ ,  $P_{5-0}$  and  $G_{5-0}$  in terms of  $C_0$ ,  $P_0$ ,  $P_1$ , ...,  $P_5$ ,  $G_0$ , ..., and  $G_5$ . Identify the critical path of the 6-bit CLA adder. How much time does it take to add two 6-bit binary numbers (i.e. the worst case delay)?



$$C_4 = G_3 + P_3 G_2 + P_3 P_2 G_1 + P_3 P_2 P_1 G_0 + P_3 P_2 P_1 P_0 C_0$$

$$/2 \quad C_5 = G_4 + P_4 G_3 + P_4 P_3 G_2 + P_4 P_3 P_2 G_1 + P_4 P_3 P_2 P_1 G_0 + P_4 P_3 P_2 P_1 P_0 C_0$$

$$C_6 = G_5 + P_5 G_4 + P_5 P_4 G_3 + P_5 P_4 P_3 G_2 + P_5 P_4 P_3 P_2 G_1 + P_5 P_4 P_3 P_2 P_1 G_0 + P_5 P_4 P_3 P_2 P_1 P_0 C_0$$

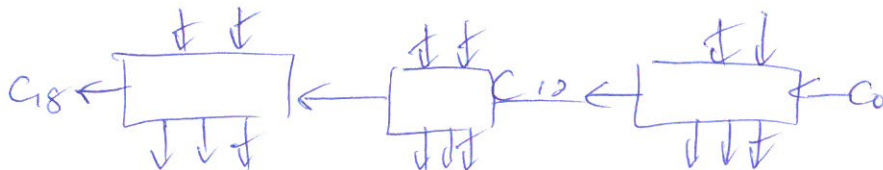
$$P_{5-0} = P_5 P_4 P_3 P_2 P_1 P_0$$

$$G_{5-0} = G_5 + P_5 G_4 + P_5 P_4 G_3 + P_5 P_4 P_3 G_2 + P_5 P_4 P_3 P_2 G_1 + P_5 P_4 P_3 P_2 P_1 G_0$$

$/3$  The critical path is  $C_0 \rightarrow C_5$ ,  $(a_i / b_i / c_0 \rightarrow s_i) C_5 \rightarrow S_5$

$$\text{The worst case delay} = 3 \tau_g + 3 \tau_g = 6 \tau_g$$

2.2 (5 marks) What is the worst case delay for three cascaded 6-bit CLAs to add together two 18-bit binary numbers?



$C_0 \rightarrow C_6$	$3 \tau_g$	}	$10 \tau_g$
$C_6 \rightarrow C_{12}$	$2 \tau_g$		
$C_{12} \rightarrow C_{17}$	$2 \tau_g$		
$C_{17} \rightarrow S_{17}$	$3 \tau_g$		

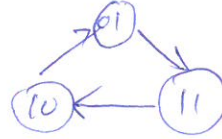
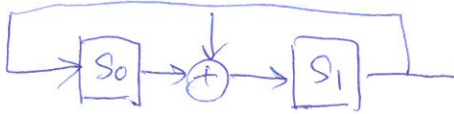


Question 5. (30 marks)

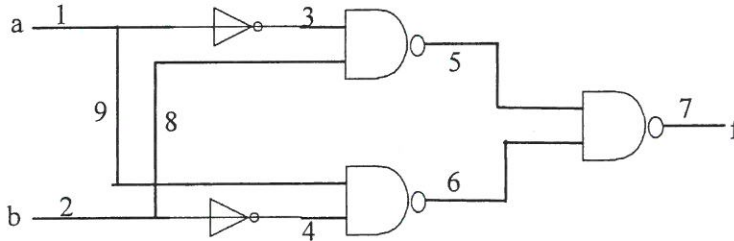
Design a test pattern generator using an autonomous linear feedback shift register and determine if it can test the circuit provided.

5.1 (7 marks) Create a degree-2 primitive polynomial  $P(x)$ . Provide the polynomial, the corresponding circuit diagram of the ALFSR and a state transition graph.

$P(x) = x^2 + x + 1$



5.2 (18 marks) Using the stuck at model for following circuit, find out one test vector for every stuck at fault on a labeled wire. Provide the input (a,b), correct output (f) and faulty output (f\*). You may wish to list additional test vectors outside the table.



Wire	Stuck at 0 abff*	Stuck at 1 abff*
1	1010 / 1101	0001 / 0110
2	0110 / 1101	0001 / 1010
3	01 10	1101
4	10 10	1101
5	00 / 11 01	01 10
6	00 / 11 01	10 10
7	1010 0110	00 / 11 01
8	01 00	00 00
9	1010	00 01

5.3 (5 marks) What is the minimum test pattern required? Can the ALFSR you designed produce all of the required test patterns?

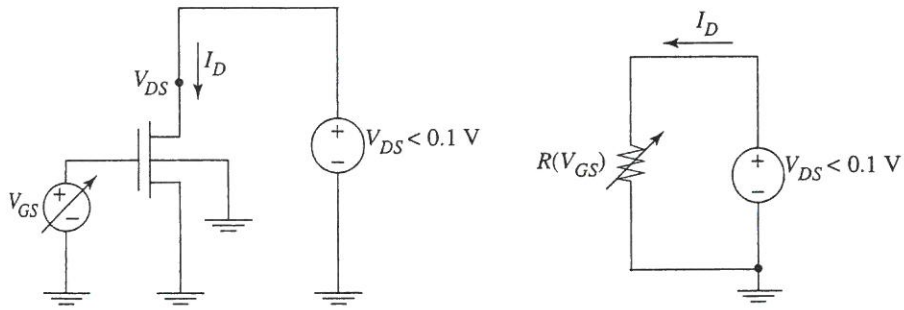
④ 01, 10, 11, 00

No.

Question 6. (15 marks)

6.1 (8 marks) The circuit below shows an n-channel MOSFET that is used as a voltage-controlled resistor. A MOSFET in this configuration is found in circuits such as variable gain amplifiers. Find the sheet resistance of the MOSFET ( $R_{\square}$ ) over the range  $V_{GS} = 1.5V$  to  $V_{GS} = 4V$  using  $\mu_n = 200 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ ,  $C_{ox} = 2.5 \text{ fF}/\mu\text{m}^2$  and  $V_{Tn} = 1V$ . Calculate a few points and plot  $R_{\square}$  versus  $V_{GS}$ .

Hint:  $R = R_{\square} (L/W)$



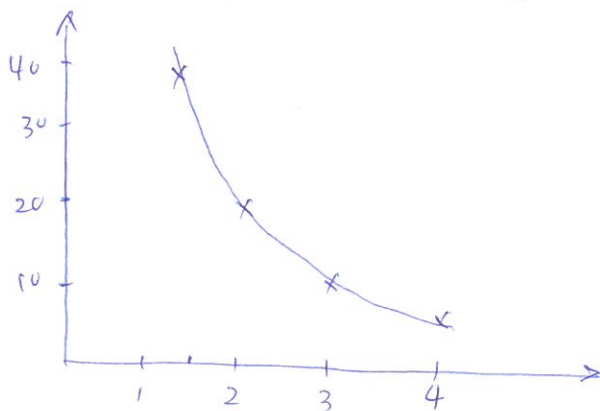
$$\therefore V_{DS} < 0.1V < [V_{GS} - V_T \geq (1.5 - 1) = 0.5V]$$

$\therefore$  Triode region

$$I_D = \mu_n \cdot C_{ox} \cdot \frac{W}{L} \left[ (V_{GS} - V_T) V_{DS} - \frac{1}{2} V_{DS}^2 \right]$$

$$R_{DS} = \frac{V_{DS}}{I_D} = \frac{L/W}{\mu_n \cdot C_{ox} \cdot (V_{GS} - 1)} = R_{\square} \cdot \frac{L}{W}$$

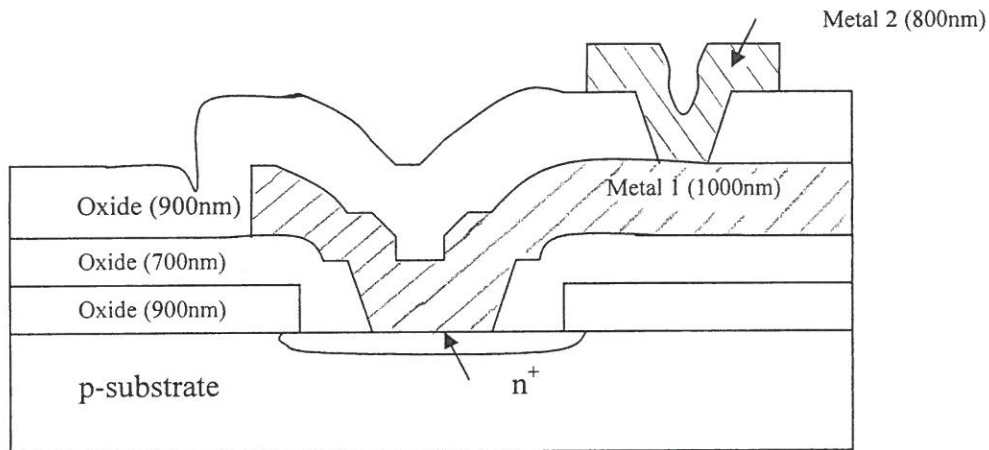
$$\therefore R_{\square} = \frac{1}{200 \text{ cm}^2/\text{V}\cdot\text{s} \times 2.5 \times 10^{-15} / 10^{-8} \text{ cm}^2} = \frac{20 \text{ k}\Omega\text{-V}}{(V_{GS} - 1)}$$





6.2 (7 marks) Suggest a process sequence for the following structure starting from a p-doped wafer (ignore cleaning). Include deposition technique, material and thickness. For example, the last two steps might be:

- Sputter 0.8  $\mu\text{m}$  of Al-Cu alloy
- Pattern M2 lines in PR, etch M2 and strip PR.



1. Grow 900 nm thermal oxide;
2. Pattern with  $n^+$  mask in PR, etch  $\text{SiO}_2$  and strip PR;
3. Ion implantation with Phosphorus + annealing;
4. ~~Sputter~~ CVD 700 nm oxide, pattern with Metal 1 contact mask, etch oxide, strip PR;
5. Sputter Al, 1000 nm, pattern with metal 1 mask, etch Al, strip PR;
6. CVD 900 nm oxide, pattern with metal 2 contact mask, etch oxide, strip PR
7. Sputter 0.8  $\mu\text{m}$  of Al-Cu alloy  
Pattern  $m_2$  lines in PR, etch  $m_2$  and strip PR